

FIG. 1 a

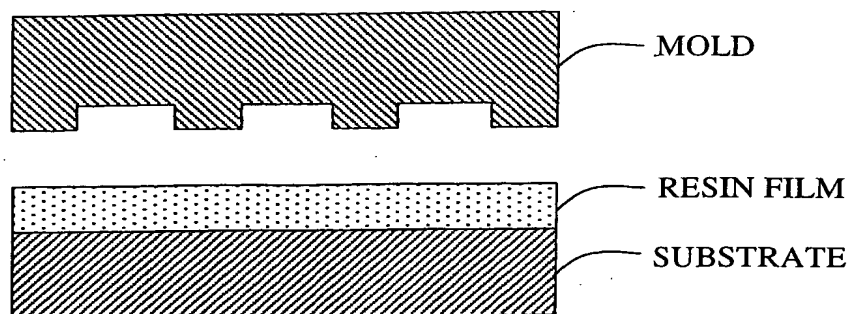


FIG. 1 b

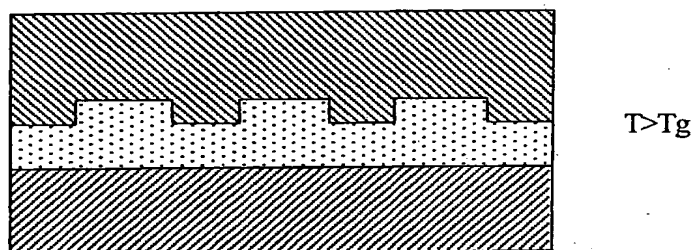


FIG. 1 c

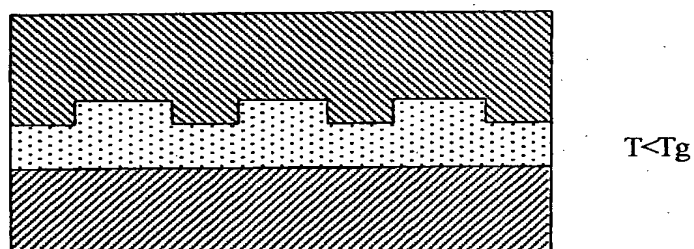


FIG. 1 d

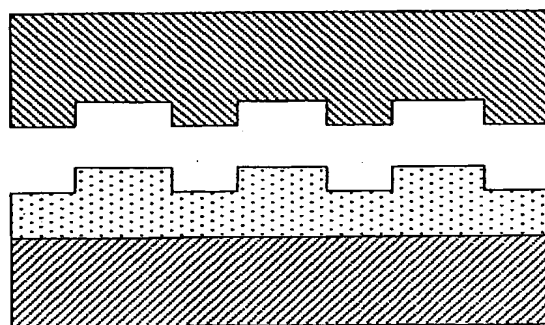


FIG. 2 A

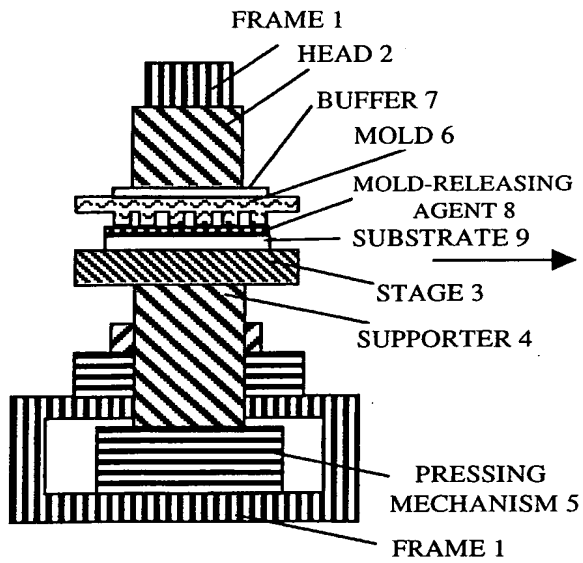


FIG. 2 B

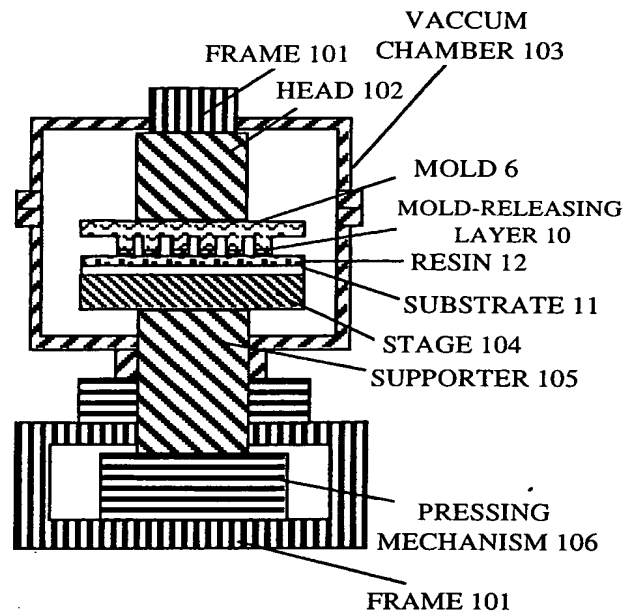


FIG. 3 A

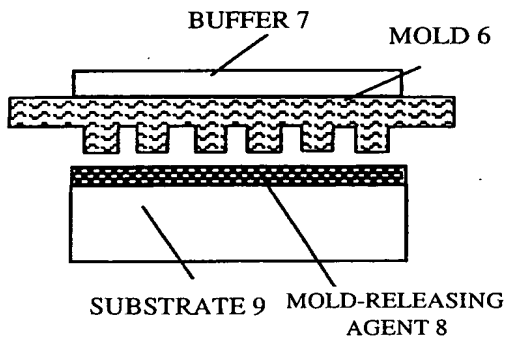


FIG. 3 B

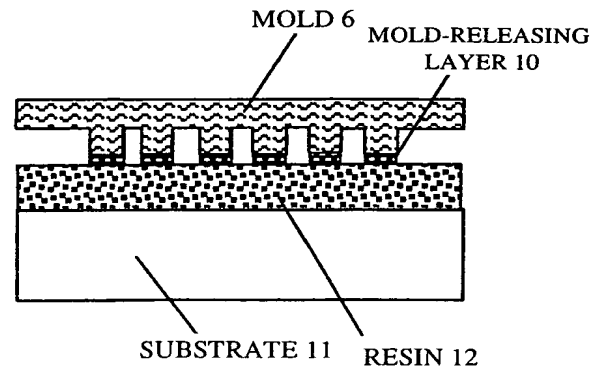


FIG. 4 a

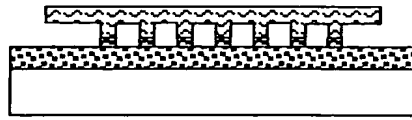


FIG. 4 b

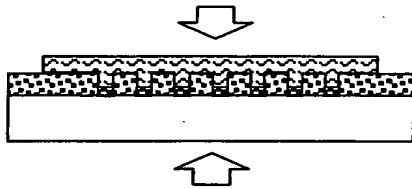


FIG. 4 c

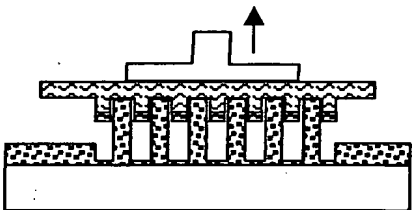


FIG. 4 d



FIG. 5

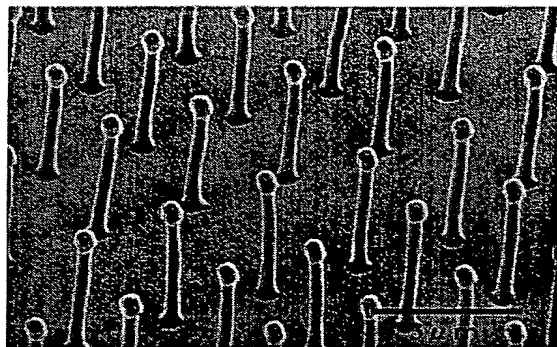


FIG. 6 a



FIG. 6 b

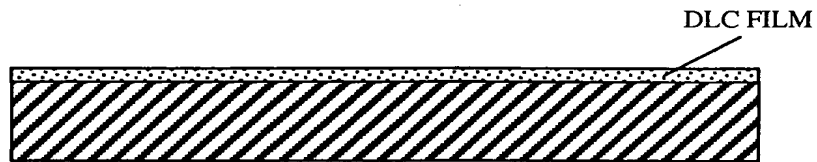


FIG. 6 c

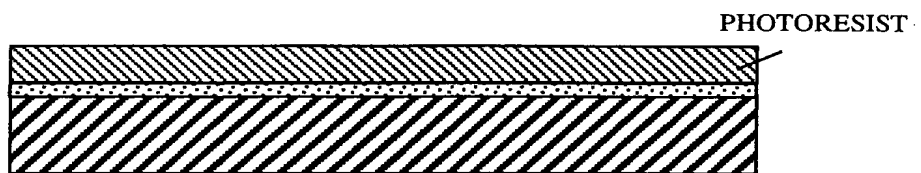


FIG. 6 d

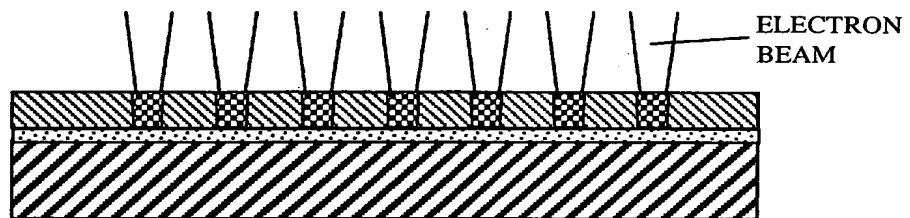


FIG. 6 e

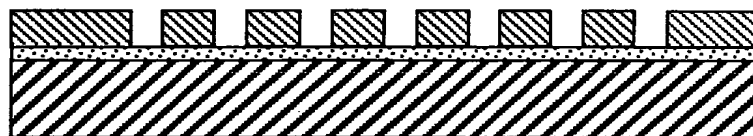


FIG. 6 f



FIG. 6 g

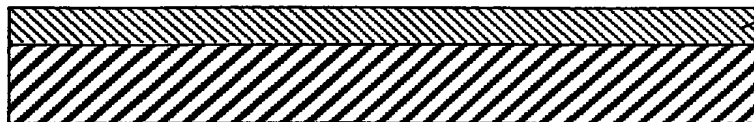


FIG. 7 a



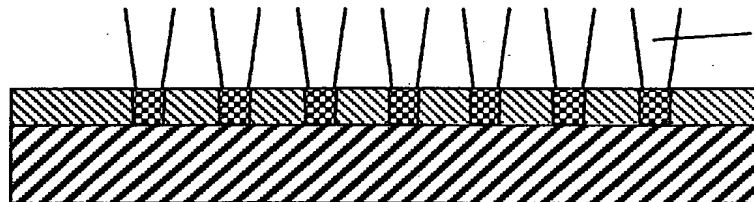
Si SUBSTRATE

FIG. 7 b



PHOTORESIST

FIG. 7 c



ELECTRON BEAM

FIG. 7 d

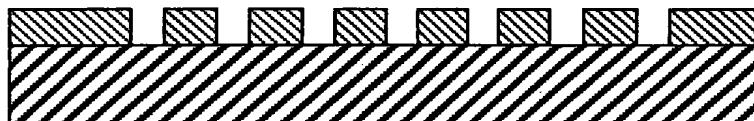


FIG. 7 e



Ni SPUTTERED FILM

FIG. 7 f



Ni PLATED FILM

FIG. 7 g

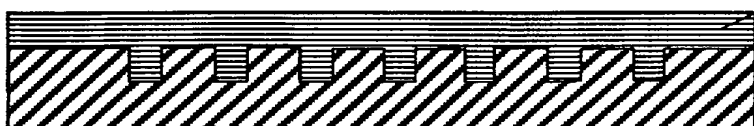


FIG. 7 h



FIG. 8

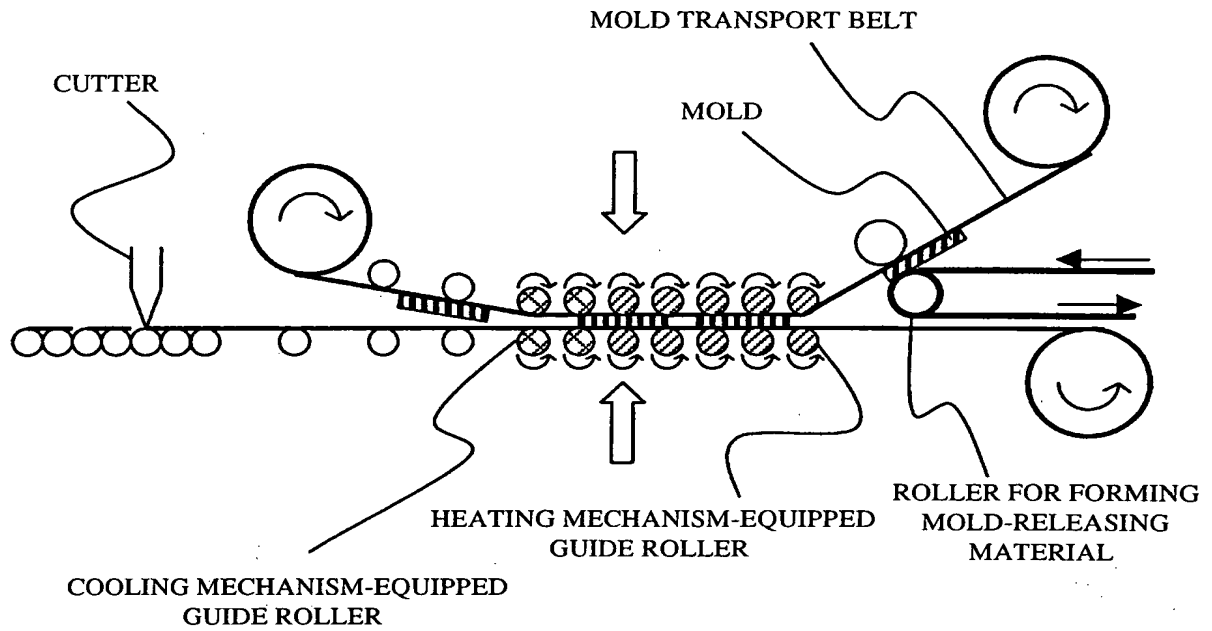


FIG. 9

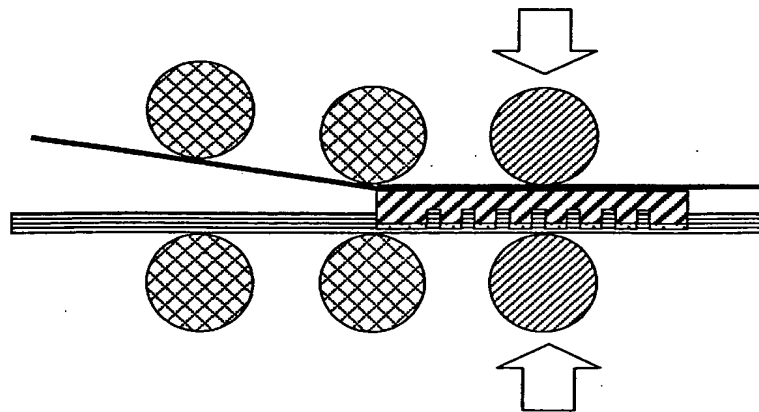


FIG. 10

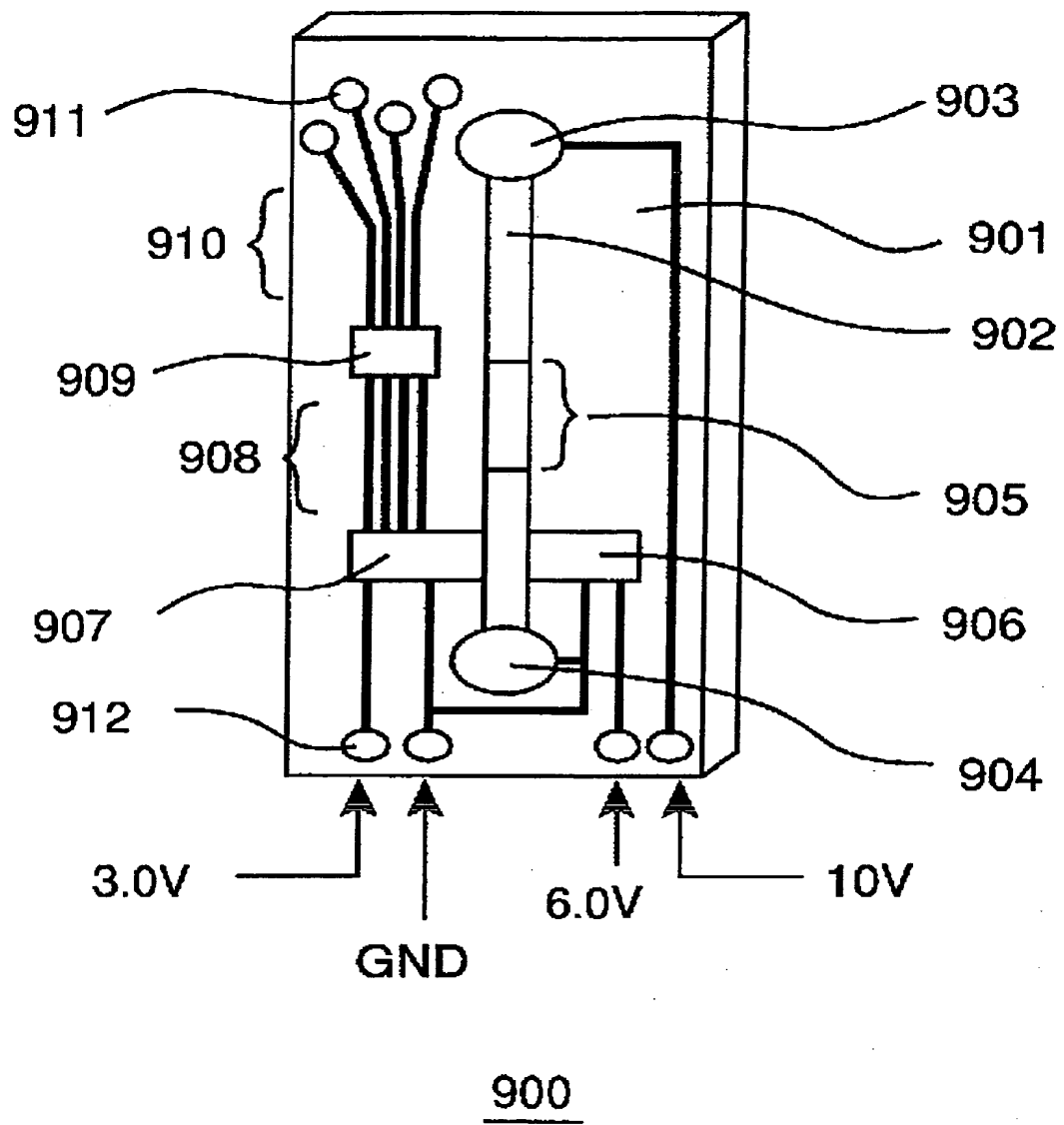




FIG. 11

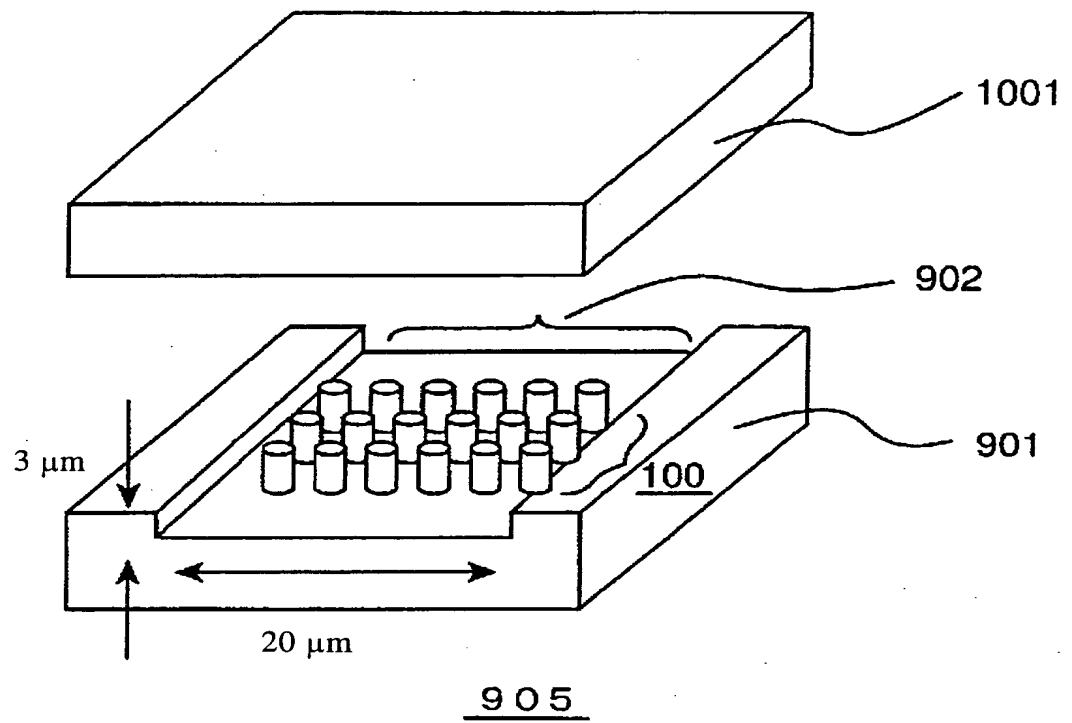
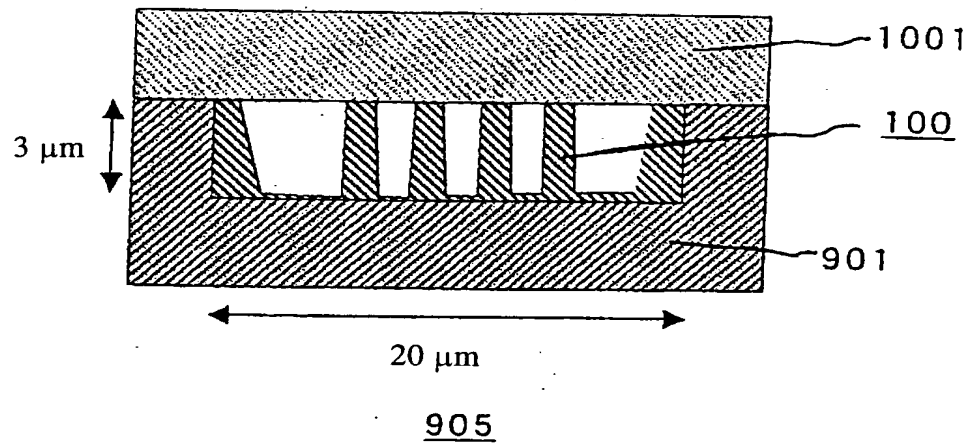


FIG. 12



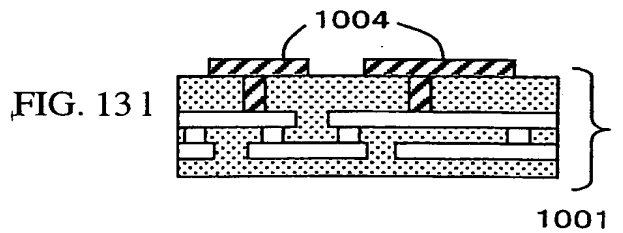
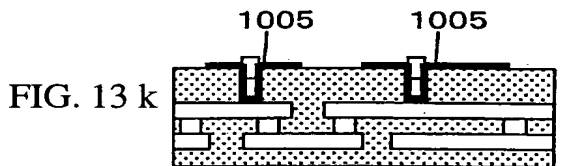
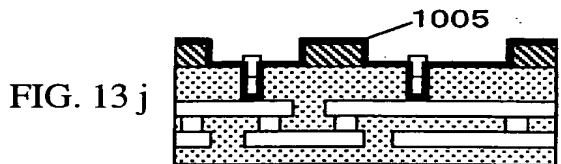
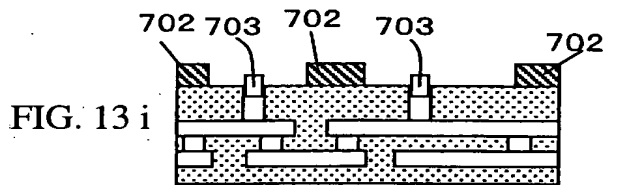
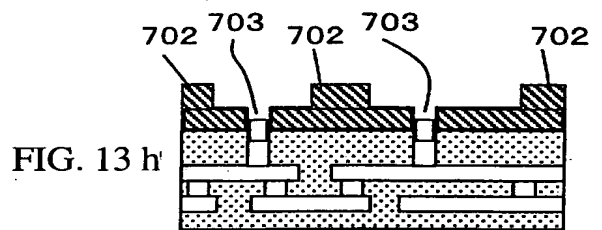
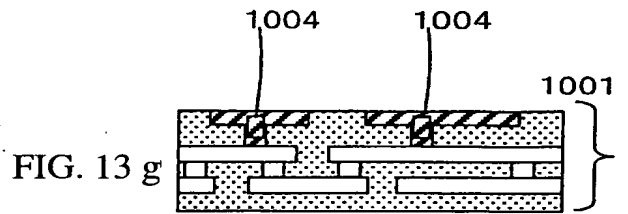
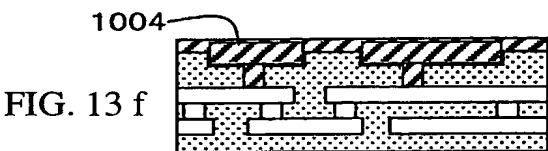
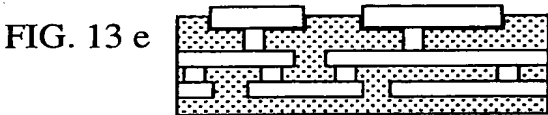
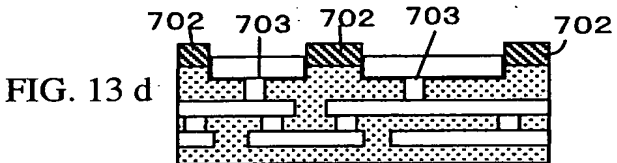
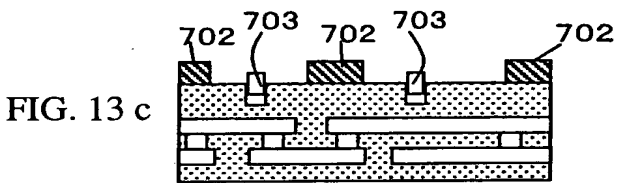
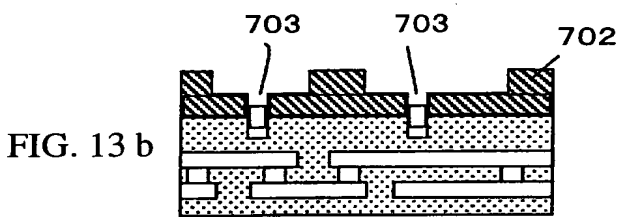
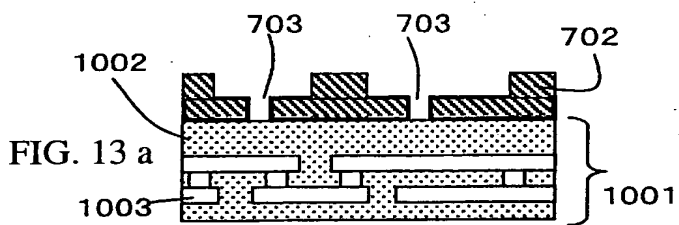
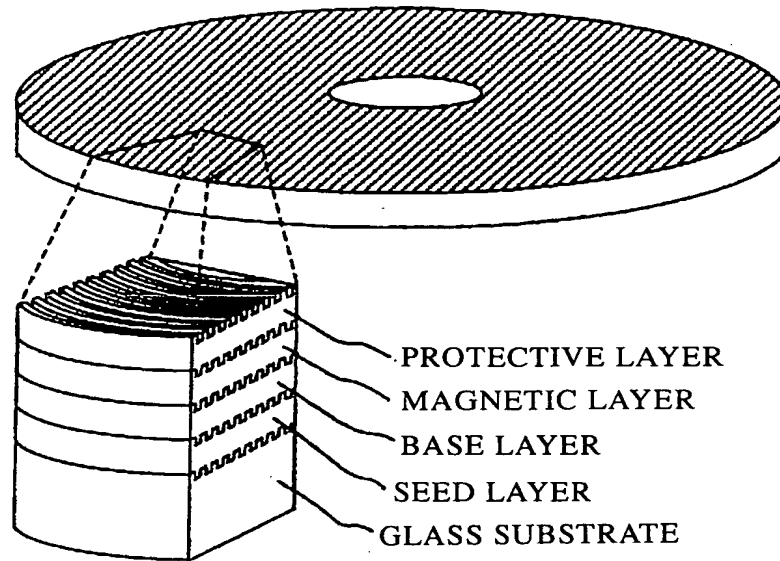


FIG. 14



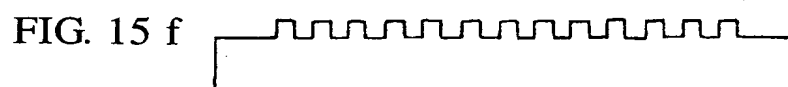
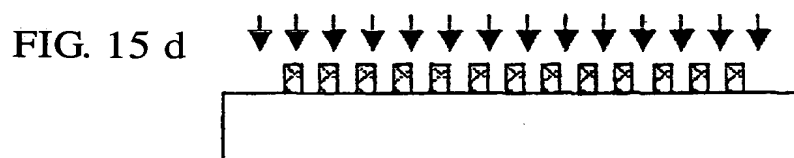
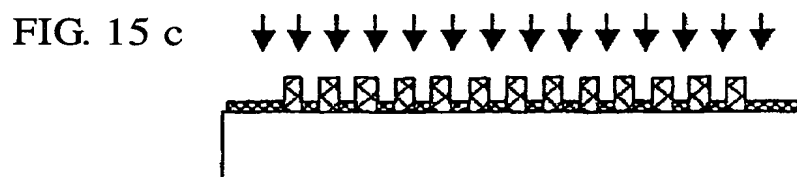
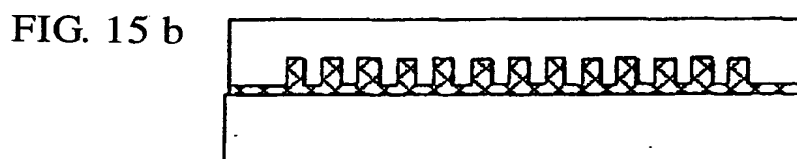
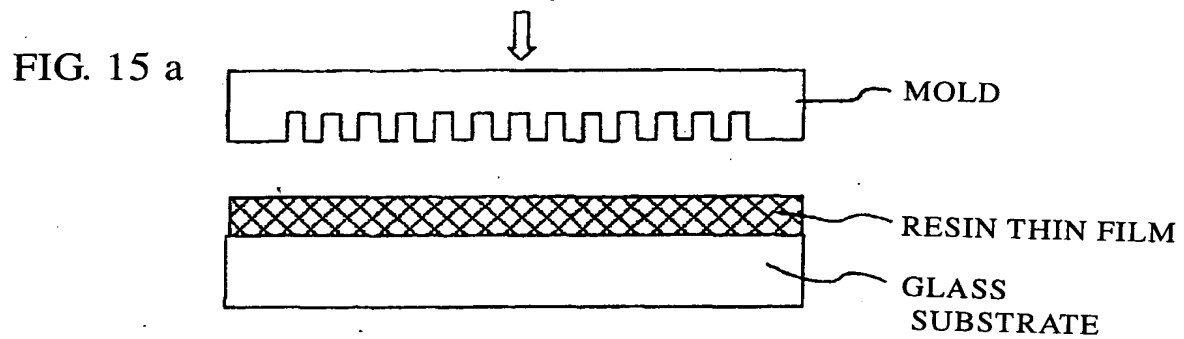


FIG. 16

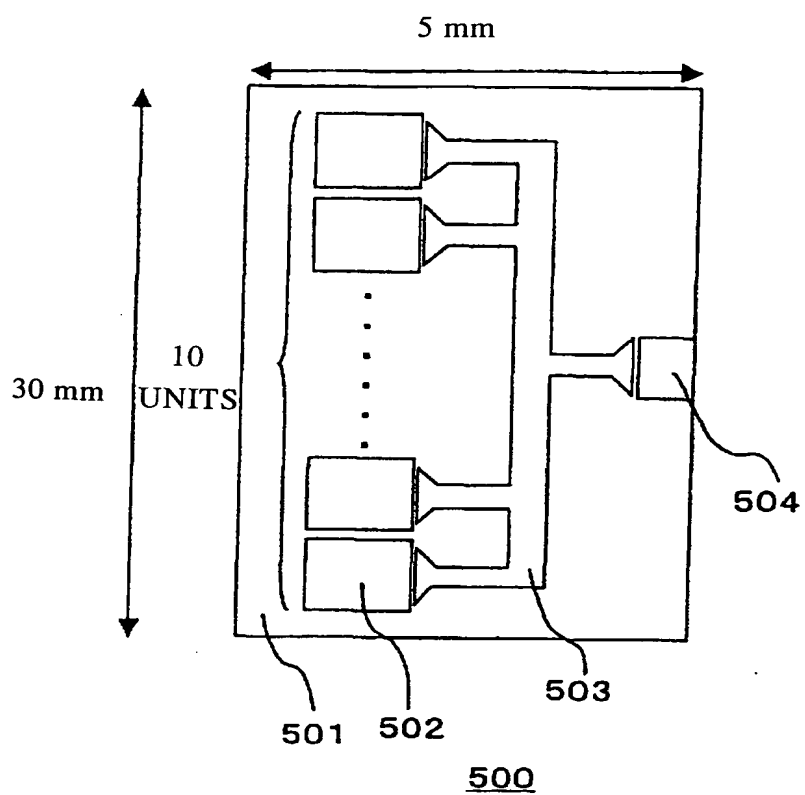


FIG. 17

